

What is claimed is:

1. An electrostatic capacitance sensor, comprising
an electrostatic capacitance detector,
an operational amplifier in which a feedback impedance
circuit is connected between an output terminal and an inverse
input terminal of said operational amplifier,
a signal line connected between said inverse input
terminal of said operational amplifier and said electrostatic
capacitance detector,
an alternating-current signal generator connected to
a non-inverse input terminal of said operational amplifier,
and
a shield for shielding at least a portion of said signal
line, said shield being connected to said non-inverse input
terminal of said operational amplifier and said
alternating-current signal generator, wherein
said electrostatic capacitance detector comprises a
detecting electrode and a shield electrode,
said detecting electrode comprises a detector-
detecting electrode for detecting an object to be detected
and an electrode introducer-detecting electrode for
introducing an electrode to said detector-detecting
electrode,
said shield electrode is connected to said shield, and

at least a portion of said electrode introducer detecting electrode is shielded by said shield electrode.

2. An electrostatic capacitance sensor as recited in claim 1, wherein

said detecting electrode and said shield electrode are flat plate ^{shaped} electrodes and laminated such that they become layers different from each other, and

said detecting electrode and said shield electrode are provided such that at least a portion of said electrode introducer-detecting electrode and said shield electrode are superposed as viewed from the laminated direction of said detecting electrode and said shield electrode.

3. An electrostatic capacitance sensor as recited in claim 1, wherein

said detector-detecting electrode and said electrode introducer-detecting electrode are shielded by said shield electrode.

4. An electrostatic capacitance sensor as recited in claim 2, wherein

said electrostatic capacitance detector further comprises a second shield electrode,

Shaped
~~e-like~~

a the

Shaped
~~like~~

Shaped
~~like~~

shield electrode and said second shield electrode are integrally formed with an insulator capable of mounting the object to be mounted.

9. An electrostatic capacitance sensor as recited in claim 1, wherein

when said electrostatic capacitance detector comprises said detecting electrode and said shield electrode, said detecting electrode and said shield electrode are covered with an insulating layer, and

when said electrostatic capacitance detector comprises said detecting electrode, said shield electrode and said second shield electrode, said detecting electrode, said shield electrode and said second shield electrode are covered with an insulating layer.

10. An object mounting body for mounting an object to be mounted, comprising a detecting electrode and a shield electrode, wherein

said detecting electrode comprises a detector-detecting electrode for detecting an object to be detected and an electrode introducer-detecting electrode for introducing an electrode to said detector-detecting electrode,

said detecting electrode and said shield electrode are flat plate-like electrodes and laminated such that they become layers different from each other, and

said detecting electrode and said shield electrode are provided such that said detecting electrode and said shield electrode are not superposed, and at least a portion of said electrode introducer-detecting electrode and said shield electrode are superposed as viewed from the laminated direction of said detecting electrode and said shield electrode.

11. An electrostatic capacitance sensor component, comprising an electrostatic capacitance detector having a detecting electrode and a first shield electrode, and a flat plate-like second shield electrode laminated with said detecting electrode such that said second shield electrode and said detecting electrode become layers different from each other, wherein

said detecting electrode comprises a detector-detecting electrode for detecting an object to be detected and an electrode introducer-detecting electrode for introducing an electrode to said detector-detecting electrode,

said detector-detecting electrode is a flat plate-like

Shaped
like

electrode, said detecting electrode and said first shield electrode are provided such that at least a portion of said first shield electrode is located on a side of said detector-detecting electrode as viewed from a direction perpendicular to a main face of said flat plate-like electrode, and

said detecting electrode and said second shield electrode are provided such that said detecting electrode and said second shield electrode are not superposed, and at least a portion of said electrode introducer-detecting electrode and said second shield electrode are superposed as viewed from ~~the~~^a laminated direction.

12. An electrostatic capacitance sensor component comprising an electrostatic capacitance detector having a detecting electrode and a first shield electrode, and a flat ~~plate-like~~^{shaped} second shield electrode laminated with said detecting electrode such that said second shield electrode and said detecting electrode become layers different from each other, wherein

said detecting electrode comprises a detector-detecting electrode for detecting an object to be detected and an electrode introducer-detecting electrode for introducing an electrode to said detector-detecting

electrode,

said detector-detecting electrode is a flat plate-like electrode, said detecting electrode and said first shield electrode are provided such that at least a portion of said first shield electrode is located on a side of said detector-detecting electrode as viewed from a direction perpendicular to a main face of said flat plate-like electrode, and

said detecting electrode and said second shield electrode are provided such that said detector-detecting electrode and said electrode introducer-detecting electrode are superposed above said second shield electrode as viewed from the laminated direction of said detecting electrode and said shield electrode.

13. An electrostatic capacitance sensor as recited in claim 2, wherein

said electrostatic capacitance detector further comprises a third shield electrode,

said third shield electrode is a flat plate-like ^{shaped} electrode and laminated with said detecting electrode ~~on the~~ opposite side from said shield electrode with respect to said detecting electrode, and

said detecting electrode and said third shield

electrode are provided such that said detector-detecting electrode and said electrode introducer-detecting electrode are superposed above said second shield electrode as viewed from the laminated direction of said detecting electrode and said shield electrode.

14. An object mounting apparatus, comprising
- an object mounting body for mounting an object,
 - at least two object detecting electrodes mounted to said object mounting body, and
 - at least two detecting circuits respectively connected to said at least two object detecting electrodes, wherein
 - each of said two detecting circuits comprises
 - an operational amplifier in which a feedback impedance circuit is connected between an output terminal and an inverse input terminal of said operational amplifier,
 - a signal line connected between said inverse input terminal of said operational amplifier and one of said at least two object detecting electrodes,
 - an alternating-current signal generator connected to a non-inverse input terminal of said operational amplifier, and
 - a shield for shielding at least a portion of said signal line, said shield being connected to said non-inverse input

further comprising at least two shield electrodes mounted to said object mounting body, wherein said at least two shield electrodes respectively shield at least portions of said at least two object detecting electrodes and said at least two shield electrodes are respectively connected to said shields of said at least two detecting circuits.

17. An object mounting apparatus as recited in claim 15, further comprising at least two shield electrodes mounted to said object mounting body, wherein said at least two shield electrodes respectively shield at least portions of said at least two object detecting electrodes and said at least two shield electrodes are respectively connected to said shields or connected to said shields through said switch.

18. An object mounting apparatus as recited in claim 16, wherein

each of said at least two object detecting electrodes comprises a detector-detecting electrode for detecting an object to be detected, and

said detector-detecting electrode is shielded by said shield electrode in at least one direction.

19. An object mounting apparatus as recited in claim 14,

wherein

said object is a flat plate-like ^{Shaped} object, and

said detector-detecting electrodes of said at least two object detecting electrodes are disposed such that when said object is mounted on said object mounting body, an arrangement of said detector-detecting electrodes is in parallel to a bottom face of said object.

20. An object mounting apparatus as recited in claim 14, wherein

said object is a flat plate-like ^{Shaped} object, and

when said object is mounted on said object mounting body, if a surface of projection obtained by projecting said object on said object mounting body is divided into at least two sub-regions such that areas of the sub-regions are equal to each other, said at least two object detecting electrodes are disposed on positions respectively corresponding to said at least two sub-regions.

21. A wafer transfer apparatus wherein

said object is a semiconductor wafer, and

said wafer transfer apparatus comprises an object mounting apparatus as recited in claim 14.

22. A substrate transfer apparatus for manufacturing a liquid crystal display device, wherein

said object is a substrate for manufacturing a liquid crystal display device, and

said substrate transfer apparatus comprises an object mounting apparatus as recited in claim 14.

SubC
23. A semiconductor manufacturing apparatus comprising a electrostatic capacitance sensor as recited in claim 1.

24. A liquid crystal display device manufacturing apparatus comprising a electrostatic capacitance sensor as recited in claim 1.